

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions and listings of claims in the application:

What is claimed is:

1. (Currently Amended) A vacuum arc deposition apparatus comprising:

[[a]] vacuum chamber;

an arc evaporation source for evaporating a cathode material from a ~~cathode~~ plurality of cathodes due to vacuum arc discharge, said arc evaporation source including

a cathode holder made from a conductor for holding said ~~cathode~~ plurality of cathodes,

[[a]] said plurality of cathodes attached to said cathode holder,

a trigger electrode for arc ignition,

a trigger drive unit for performing an operation to change over a position of said trigger electrode to a changed-over position to thereby position said trigger electrode in front of a desired one of said plurality of cathodes and an operation to move said trigger electrode toward or to get apart from said desired ~~cathode~~ one of said plurality of cathodes in said changed-over position,

a shutter capable of covering fronts of all of said plurality of cathodes except said ~~desired cathode~~ desired one of said plurality of cathodes , and

a shutter drive unit for performing an operation to move said shutter to thereby change over to a cathode of said plurality of cathodes not covered with said shutter;

an arc power supply connected between said cathode holder of said arc evaporation source and an anode corresponding to said cathode holder with said ~~cathode on a negative side~~ said plurality of cathodes on a negative side; and

a changeover control unit for making a changeover control to control said shutter drive unit and said trigger drive unit so as to change over to a cathode of said plurality of cathodes not covered with said shutter while positioning said trigger electrode in front of ~~said cathode~~ a cathode of said plurality of cathodes not covered with said shutter.

2. (Original) A vacuum arc deposition apparatus according to Claim 1, further comprising:

an arc current integrator for integrating an arc current flowing into said arc power supply via said cathode holder during current-carrying time so as to obtain an arc current amount,

wherein said changeover control unit performs said changeover control whenever said arc current amount obtained by said arc current integrator exceeds a predetermined reference value.

3. (Original) A vacuum arc deposition apparatus according to Claim 1, wherein said shutter is made from metal, and said vacuum arc deposition apparatus further comprising:

a resistor connected between said shutter and said anode;

an ampere meter for measuring a current flowing into said shutter via said resistor; and

a shut-down control unit for making a shut-down control for shutting down an output of said arc power supply when said current measured by said ampere meter exceeds a predetermined reference value.

4. (Original) A vacuum arc deposition apparatus according to Claim 1, wherein said vacuum chamber serves as said anode.

5. (Currently Amended) A vacuum arc deposition apparatus according to Claim 1, wherein the said plurality of cathodes are two cathodes, and said shutter is larger than a surface, from which the cathode material is evaporated, of one of the two cathodes so that said shutter ~~cover~~ covers the one of the two cathodes.

6. (Currently Amended) A vacuum arc deposition apparatus according to Claim 1, wherein said shutter has an opening portion which is larger than a surface, from which the cathode material is evaporated, of one of the plurality of cathodes, and said shutter covers surfaces, each from which the cathode material is evaporated, of the other ones of the plurality of cathodes.

7. (Currently Amended) A vacuum arc deposition apparatus according to Claim 1, wherein said trigger electrode and said shutter are disposed with different distances from surfaces of the said plurality of cathodes each from which the cathode

material is evaporated.

8. (Original) A vacuum arc deposition apparatus according to Claim 1, wherein said plurality of cathodes are made of the same material.

9. (Original) A vacuum arc deposition apparatus according to Claim 1, wherein said plurality of cathodes are made of different materials.

10. (Currently Amended) A vacuum arc deposition apparatus according to Claim 1, wherein said plurality of cathodes are at least three cathodes where the at least three cathodes of the same kind and of different kinds are mixed.